

1-17-1

SHEET 1 OF 2

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)			ATTY. DOCKET NO. 49959-118		SERIAL NO. 09/645,690	
			APPLICANT Lizhong Sun, et al.			
			FILING DATE August 24, 2000		GROUP 2812 1746	

U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
SW	3,889,753	6/17/1975	Richardson	/	/	/
	4,090,563	5/23/1978	Lybarger, et al.			
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						Yes	No
SW	0 401 147	12/5/1990	EPO	/	/	/	/
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	2 722 511	1/19/1996	FR				
	V	0 860 860	8/26/1998				

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
SW	Hymes, et al., "The Challenges of the Copper CMP Clean", <i>Semiconductor International</i> , pp. 117-122 (1998). Pak, "Impact of EDTA on Junction and Photolith Qualities", <i>Extended Abstracts</i> , October 1980, vol. 80, no. 2, pp 1241-1243.
EXAMINER 	DATE CONSIDERED 8/18/02

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.